1 1230 (134902).CCLS.	1 Number	Llite	Coarch Toxt	, I DB	Time stome
10 95 239/567 CCLS. US-PGPUB US-	L Number	Hits	Search Text	DB	Time stamp
2003/01/03 13:17	'	1230	(134/302).COLO.		2003/01/03 12:50
239/567 and taper\$3	7	670	(230/567) CCL S		2002/04/02 42:47
10	'	670	(239/307).CCLS.		2003/01/03 13:17
13	10	05	220/567 and tanash2		0000/04/02 40:07
13	10	95	239/567 and taper\$3		2003/01/03 13:27
129	40	00	000/507		0000/04/00 40:00
129	13	29	239/567.ccis. and taper\$3		2003/01/03 13:28
17		400	(450/045.00) 001.0	1	0000/04/00 44.07
18	4	129	(155/345.33).CCLS.		2003/01/03 14:27
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- 970 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) same (wafer substrate) - 2 (("5728260") or ("5618349")).PN. - 2 ("5728260") or ("5618349")).PN. - 3 (6 5618349.URPN 4 (6 5618349.URPN 5024194.URPN 50] -	3080			2002/08/23 10:49
- 299 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) same (wafer substrate) US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; USPAT USPAT 2002/08/23 11:06 USPAT 2002/08/23 11:11 USPAT; USPAT 2002/08/23 11:11 USPAT USPAT; USPAT 2002/08/23 11:11 USPAT; USPA]				
- 299 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) same (wafer substrate) - 2 (("5728260") or ("5618349")).PN 0 5728260.URPN 0 5728260.URPN 0 65618349.URPN 0 6402849.URPN 1 6204194.URPN 1 6204194.URPN 1 2002/08/23 11:14 - 12 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) same (wafer substrate) wertical - 234 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 1 ("5551165").PN 494 (137/561r).CCLS 299 pressure same (gas with (passage inlet tube) with (reduc\$3 USPAT; US-PGPUB]-	970			2002/08/23 10:52
narrow\$3 minimiz\$3 restrict)) same (wafer substrate) ("5728260") or ("5618349")).PN. US-PGPUB USPAT; US-PGPUB USPAT US-PGPUB USPAT US-PGPUB USPAT US-PGPUB USPAT USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				US-PGPUB	
- 2 (("5728260") or ("5618349")).PN. - 0 5728260.URPN 6 5618349.URPN 0 6402849.URPN 1 6204194.URPN 12 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) same (wafer substrate) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 1 ("5551165").PN. - 494 (137/561r).CCLS. USPAT 2002/08/23 11:11 USPAT; USPAT; USPAT; US-PGPUB USPAT; 2002/08/23 13:28] -	299			2002/08/23 13:28
- 0 5728260.URPN. 5618349.URPN. 66402849.URPN. 6402849.URPN. 6204194.URPN. 6204194.URPN. 12 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) same (wafer substrate) same vertical pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 234 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 1 ("5551165").PN. USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; 2002/08/23 14:08	<u> </u>			US-PGPUB	
- 0 5728260.URPN 6 5618349.URPN 0 6402849.URPN 10 6204194.URPN 12 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) same (wafer substrate) same vertical pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 1 ("5551165").PN 494 (137/561r).CCLS 494 (137/561r).CCLS 2002/08/23 11:06 - USPAT USPAT 2002/08/23 11:11 - US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; 2002/08/23 14:08	j -	2	(("5728260") or ("5618349")).PN		2002/08/23 10:55
- 6 5618349.URPN 00 6402849.URPN 11 6204194.URPN 12 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) same (wafer substrate) same vertical pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 234 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 1 ("5551165").PN 494 (137/561r).CCLS 494 (137/561r).CCLS.					
- 0 6402849.URPN 1 6204194.URPN 12 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) same (wafer substrate) same vertical pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 234 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 1 ("5551165").PN 494 (137/561r).CCLS 494 (137/561r).CCLS.] -				l .
1 6204194.URPN. 12 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) same (wafer substrate) same vertical pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) 1 ("5551165").PN. 2002/08/23 11:19 2002/08/23 11:29 DERWENT USPAT; U	-	6		USPAT	2002/08/23 11:11
- 234 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) same (wafer substrate) same vertical pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 1 ("5551165").PN. - 494 (137/561r).CCLS. USPAT; US-PGPUB USPAT; US-PGPUB USPAT; 2002/08/23 14:08	-	0			2002/08/23 11:12
narrow\$3 minimiz\$3 restrict)) same (wafer substrate) same vertical - 234 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 1 ("5551165").PN. - 494 (137/561r).CCLS. US-PGPUB	-				2002/08/23 11:14
- 234 vertical pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 1 ("5551165").PN 494 (137/561r).CCLS. JPO; DERWENT USPAT; US-PGPUB USPAT; US-PGPUB USPAT; 2002/08/23 14:08	-	12		USPAT;	2002/08/23 11:19
- 234 pressure same (gas with (passage inlet tube) with (reduc\$3 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 1 ("5551165").PN. - 494 (137/561r).CCLS. DERWENT USPAT; US-PGPUB USPAT; 2002/08/23 14:08				US-PGPUB	
- 1 narrow\$3 minimiz\$3 restrict)) and (wafer substrate) - 1 ("5551165").PN. - 494 (137/561r).CCLS. DERWENT USPAT; US-PGPUB USPAT; 2002/08/23 14:08					
- 1 ("5551165").PN. USPAT; 2002/08/23 13:28 US-PGPUB USPAT; 2002/08/23 14:08	j -	234		JPO;	2002/08/23 11:22
- 494 (137/561r).CCLS. US-PGPUB USPAT; 2002/08/23 14:08				DERWENT	
- 494 (137/561r).CCLS. USPAT; 2002/08/23 14:08	-	1	("5551165").PN.		2002/08/23 13:28
US-PGPUB US-PGPUB	-	494	(137/561r).CCLS.	USPAT;	2002/08/23 14:08
				US-PGPUB	

	318	(137/561a).CCLS.	USPAT;	2002/08/23 14:08
	310	(10170014).0020.	US-PGPUB	2002/00/25 14.00
_	12	2652069.URPN.	USPAT	2002/08/23 14:13
	6	3650292.URPN.	USPAT	2002/08/23 14:15
-	8	4809744.URPN.	USPAT	2002/08/23 14:15
-	1			
-	4	5095930.URPN.	USPAT	2002/08/23 14:18
-	2	5029598.URPN.	USPAT	2002/08/23 14:21
-	27	3777987.URPN.	USPAT	2002/08/23 14:24
-	8	4809744.URPN.	USPAT	2002/08/23 14:28
-	0	6220286.URPN.	USPAT	2002/08/23 15:04
-	31	4989540.URPN.	USPAT	2002/08/23 15:09
-	31	4989540.URPN.	USPAT	2002/08/23 15:14
-	1	"4430149".PN.	USPAT	2002/08/23 15:14
-	2	5789322.URPN.	USPAT	2002/08/23 15:34
-	0	20010025605.URPN.	USPAT	2002/08/23 16:21
-	0	7037832.URPN.	USPAT	2002/08/23 16:53
-	0	8199359.URPN.	USPAT	2002/08/23 16:55
_	6	5618349.URPN.	USPAT	2002/08/23 16:57
-	1	6204194.URPN.	USPAT	2002/08/23 16:59
_	10	5330352.URPN.	USPAT	2002/08/23 17:09
<u>-</u>	662	118/715.ccls. and (vertical)	USPAT;	2002/08/23 17:23
	002	Trovinosis. una (vortiour)	US-PGPUB	2002/00/25 17.25
	189	118/715.ccls. and (vertical same (inner outer))	USPAT:	2002/08/23 18:42
_	103	i 11077 13.0013. and (vertical same (inner outer))	US-PGPUB	2002/06/23 16:42
	14	4992301.URPN.		2002/00/22 40:02
_			USPAT	2002/08/23 18:23
-	0	6248672.URPN	USPAT	2002/08/23 18:24
-	9	5551984.URPN.	USPAT	2002/08/23 18:24
-	8	5164012.URPN.	USPAT	2002/08/23 18:31
-	21	vertical same ((inner outer) with tube) same (gas with (curv\$3	USPAT;	2002/08/23 18:49
	_	convex concave surroud\$3))	US-PGPUB	
-	7	vertical same ((inner outer) with tube) same (gas with (curv\$3	EPO; JPO;	2002/08/23 18:48
		convex concave surroud\$3))	DERWENT	
-	126	((inner outer) with tube) same (gas with (curv\$3 convex	EPO; JPO;	2002/08/23 18:49
		concave surroud\$3))	DERWENT	, i
-	4	((inner outer) with tube) same (gas with (curv\$3 convex	EPO; JPO;	2002/08/23 18:50
		concave surroud\$3)) and (wafer substrate semiconductor)	DERWENT	
-	57	((inner outer) with tube) same (gas with (curv\$3 convex	USPAT;	2002/08/23 19:06
	1	concave surroud\$3)) and (wafer substrate semiconductor)	US-PGPUB	
-	3305	(gas with (curv\$3 convex concave surroud\$3)) and (wafer	USPAT;	2002/08/23 19:15
		substrate semiconductor)	US-PGPUB	
_	2238	(gas with (curv\$3 convex concave surroud\$3)) and (wafer	USPAT;	2002/08/23 19:07
		substrate semiconductor) and (deposit\$3 etch\$3)	US-PGPUB	2302/03/20 13.07
_	47	137/\$.ccls. and (gas with (curv\$3 convex concave surroud\$3)	USPAT;	2002/08/23 19:16
	7') and (wafer substrate semiconductor)	· ·	2002/06/23 18.10
_	1	("5164012").PN.	US-PGPUB	2002/08/02 40:40
] -	'	(3 1040 12).FIN.	USPAT;	2002/08/26 10:16
		474E000 DN	US-PGPUB	0000/00/00 00 10
-	1	"4745088".PN.	USPAT	2002/08/26 09:19
-	1	("5505385").PN.	USPAT;	2002/08/26 10:17
		//	US-PGPUB	
	1	_(US-2652069-\$).did.	USOCR	2002/08/26 10:35

-	19	((US-6303906-\$ or US-6139642-\$ or US-5777300-\$ or	USPAT;	2002/08/26 10:58
		US-5750436-\$ or US-5728260-\$ or US-5637153-\$ or	US-PGPUB;	
		US-5622566-\$ or US-5500388-\$ or US-5441570-\$ or	JPO;	
		US-5307568-\$ or US-5151133-\$ or US-5002011-\$ or	DERWENT	
ļ		US-5618349-\$ or US-5522936-\$ or US-6402849-\$ or		
		US-6204194-\$ or US-4745088-\$ or US-5095930-\$ or		
		US-5029598-\$ or US-4809744-\$ or US-4609010-\$ or		
		US-3650292-\$ or US-5505385-\$ or US-3777987-\$ or		
		US-6352084-\$ or US-3601320-\$).did. or (US-5578132-\$ or		
		US-5520742-\$ or US-5509967-\$ or US-5318633-\$ or		
		US-5279670-\$ or US-5127365-\$ or US-5950675-\$ or		
		US-4275752-\$ or US-6435865-\$ or US-6296710-\$ or		
		US-6026764-\$ or US-5164012-\$ or US-4992301-\$ or		
		US-6248672-\$ or US-5618351-\$).did. or		
		(US-20010025605-\$).did. or (JP-58197724-\$ or		
		JP-11006068-\$ or JP-11154670-\$ or JP-08199359-\$ or		
		JP-09036047-\$ or JP-08083774-\$ or JP-07058030-\$ or		
		JP-04206715-\$ or JP-02025574-\$ or JP-02025575-\$ or		
		JP-02025576-\$ or JP-60024375-\$).did. or (JP-58197724-\$ or		
		JP-11302851-\$ or JP-11012085-\$ or JP-2001237227-\$ or		
		EP-810630-\$ or JP-09213640-\$ or JP-08199359-\$ or		
		US-20010025605-\$ or JP-07037832-\$ or JP-05047677-\$ or		
		JP-04206715-\$).did.) and vacuum		
-	1	"58197724"	JPO	2002/08/26 11:10
-	6	(("3777987") or ("5029598") or ("5441570") or ("5500388") or	USPAT:	2002/08/26 11:11
		(<u>"550538</u> 5") or (<u>"6352084"</u>)).PN.	US-PGPUB	